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Serial#	Patent#	Status	Date Filed	Title	Inventor Name
08494629	<u>5563104</u>	150	06/23/1995	REDUCTION OF PATTERN SENSITIVITY IN OZONE-TEOS DEPOSITION VIA A	JANG , SYUN-MING
08494630	Not Issued	168	06/23/1995	UNDERLAYER TO REDUCE PATTERN SENSITIVITY OF OZONE-TEOS	JANG , SYUN-MING
08494638	<u>5536681</u>	150	06/23/1995	PE-OX/OZONE-TEOS GAP FILLING CAPABILITY BY SELECTIVE N2 TREATMENT ON	JANG , SYUN-MING
08507140	Not Issued	168	07/26/1995	MULTI-COATING METHOD FOR SILICON OXIDE INSULATING LAYER	JANG , SYUN-MING
08507537	Not Issued	161	07/26/1995	MULTI-COATING METHOD YIELDING SILICON OXIDE INSULATING LAYER	JANG , SYUN-MING
08518706	<u>5518959</u>	150	08/24/1995	METHOD FOR SELECTIVELY DEPOSITING SILICON OXIDE SPACER LAYERS	JANG , SYUN-MING
08520595	<u>5631197</u>	150	08/30/1995	SACRIFICIAL ETCHBACK LAYER FOR IMPROVED SPIN-ON-GLASS PLANARIZATION	
08558491	<u>5599740</u>	150	11/16/1995	DEPOSIT-ETCH-DEPOSIT OZONE/TEOS INSULATOR LAYER METHOD	JANG , SYUN-MING
08559051	5552344	150	11/16/1995	NON-ETCHBACK SELF-ALIGNED VIA SIZE REDUCTION METHOD EMPLOYING OZONE	JANG , SYUN-MING
08563142	5552017	150	1 :	METHOD FOR IMPROVING THE PROCESS UNIFORMITY IN A	JANG , SYUN-MING

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08606955	5 <u>7/0.07/3</u> -7/	150	02/26/1996	PE CVD SILICON NITRIDE FOR ETCH STOP MASK AND OZONE TEOS PATTERN	JANG , SYUN-MING
08616411	5840624	. 150	03/15/1996	REDUCTION OF VIA OVER ETCHING FOR BORDERLESS CONTACTS	JANG , SYUN-MING
08616852	5622894	150	03/15/1996	PROCESS TO MINIMIZE A SEAM IN TUNGSTEN FILLED CONTACT HOLES	
08620182	<u>5904573</u>	150	03/22/1996	PE-TEOS PROCESS	JANG , SYUN-MING
08625278	5674783	150	04/01/1996	METHOD FOR IMPROVING THE CHEMICAL-MECHANICAL POLISH (CMP) UNIFORMITY	JANG , SYUN-MING
08635830	Not Issued	166	04/22/1996	METHOD OF MANUFACTURING A SEMICONDUCTOR IC DEVICE HAVING A MULTILAYER	JANG , SYUN-MING
08638669	Not Issued	166	04/29/1996	METHOD FOR REDUCING CONTACT RESISTANCE BETWEEN TITANIUM AND TITANIUM	JANG , SYUN-MING
08661286	<u>5817571</u>	150	06/10/1996	MULTILAYER INTERLEVEL DIELECTRICS USING PHOSPHORUS-DOPED GLASS	JANG , SYUN-MING
08666160	Not Issued	61	06/19/1996	METHOD FOR REDUCING THE PATTERN SENSITIVITY OF OZONE ASSISTED	JANG , SYUN-MING
08697699	Not Issued	71	08/27/1996	SANDWICH COMPOSITE DIELECTRIC LAYER YIELDING IMPROVED INTEGRATED	JANG , SYUN-MING
08701363	<u>5872042</u>	150	08/22/1996	METHOD FOR ALIGNMENT MARK REGENERATION	JANG , SYUN-MING
08720638	<u>5674784</u>	150	10/02/1996	METHOD FOR FORMING POLISH STOP LAYER FOR CMP PROCESS	
08729735	Not Issued	61	10/07/1996	METHOD FOR POST PLANARIZATION METAL PHOTOLITHOGRAPHY	JANG , SYUN-MING
<u>08734067</u>	5773360	150	10/18/1996	REDUCTION OF SURFACE CONTAMINATION IN POST-CMP CLEANING	JANG , SYUN-MING
<u>08743566</u>	Not Issued	161	11/04/1996	MULTI-COATING METHOD FOR SILICON OXIDE INSULATING LAYER	JANG , SYUN-MING

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Serial#	Patent#	Status	Date Filed	Title	Inventor Name
08759242	<u>5721172</u>	7150	12/02/1996	SELF-ALIGNED POLISH STOP LAYER HARD MASKING METHOD FOR FORMING	JANG , SYUN-MING
08764288	<u>5871886</u>	150	::	NOVEL SANDWICHED MIDDLE ANTIREFLECTION COATING (SMARC) PROCESS	JANG , SYUN-MING
08767015	<u>5786260</u>	150	12/16/1996	METHOD OF FABRICATING A READABLE ALIGNMENT MARK STRUCTURE USING	JANG , SYUN-MING
<u>08794597</u>	Not Issued	161	02/03/1997	METHOD OF FORMING SHALLOW TRENCH ISOLATION BY HDPCVD OXIDE	JANG , SYUN-MING
08810389	<u>5817566</u>	150	03/03/1997	TRENCH FILLING METHOD EMPLOYING OXYGEN DENSIFIED GAP FILLING	JANG , SYUN-MING
08810390	<u>5702977</u>	150	03/03/1997	SHALLOW TRENCH ISOLATION METHOD EMPLOYING SELF-ALIGNED AND PLANARIZED	JANG , SYUN-MING
<u>08820467</u>	<u>5869384</u>	150	03/17/1997	TRENCH FILLING METHOD EMPLOYING SILICON LINER LAYER AND GAP FILLING	JANG , SYUN-MING
08826710	<u>5817567</u>	150	04/07/1997	SHALLOW TRENCH ISOLATION METHOD	JANG , SYUN-MING
08826712	5858623	<u> </u>	04/07/1997	METHOD FOR ATTENUATING PHOTORESIST LAYER OUTGASSING	JANG , SYUN-MING
08839417	Not Issued	41	04/14/1997	METHOD FOR REDUCING	JANG,

•				CONTACT RESISTANCE BETWEEN TITANIUM AND TITANIUM	SYUN-MING
08850133	<u>5858588</u>	150	83	METHOD FOR RECOVERING ALIGNMENT MARKS AFTER CHEMICAL	JANG , SYUN-MING
08850135	<u>5726090</u>	150	05/01/1997	GAP-FILLING OF O3-TEOS FOR SHALLOW TRENCH ISOLATION	JANG , SYUN-MING
08857160	<u>5731241</u>	150	05/15/1997	SELF-ALIGNED SACRIFICIAL OXIDE FOR SHALLOW TRENCH ISOLATION	JANG , SYUN-MING
08867312	Not Issued	95	06/02/1997	METHOD TO PROTECT ALIGNMENT MARK IN CMP PROCESS	JANG , SYUN-MING
08873836	<u>5741740</u>	150	06/12/1997	SHALLOW TRENCH ISOLATION (STI) METHOD EMPLOYING GAP FILLING SILICON	JANG , SYUN-MING
08876728	Not Issued	124		METHOD OF MANUFACTURING A SEMICONDUCTOR IC DEVICE HAVING A MULTILAYER	JANG , SYUN-MING
08887401	Not Issued	71	07/02/1997	METHOD FOR FABRICATING A SHALLOW TRENCH ISOLATION USING SELECTIVE WET	JANG , SYUN-MING
08891088	Not Issued	83		METHOD FOR PHOTO ALIGNMENT AFTER CMP PLANARIZATION	JANG , SYUN-MING
08892220	Not Issued	93		NOVEL METHOD FOR FORMING INTERMETAL DIELECTRIC	JANG , SYUN-MING
08907265	<u>5804498</u>	150	08/06/1997	METHOD OF MAKING AN UNDERLAYER TO REDUCE PATTERN SENSITIVITY OF	JANG , SYUN-MING
08990699	Nổt Issued	71	12/15/1997	DIELECTRIC HARD MASK PLASMA ETCHBACK METHOD FOR FORMING A PATTERNED	JANG , SYUN-MING
09022580	Not Issued	30	02/12/1998	MULTI-COATING METHOD YIELDING SILICON OXIDE INSULATING LAYER	JANG , SYUN-MING
<u>09044763</u>	Not Issued	30	15 1	NEW VLSIC PATTERNING PROCESS	JANG , SYUN-MING

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*	<u>09067262</u> Not Iss	ued 30	04/27/1998	METHOD OF PHOTO	JANG,
20000				ALIGNMENT FOR SHALLOW	SYUN-MING
(100000)				TRENCH ISOLATION WITH	
				CHEMICAL	
	09072995 Not Iss	ued 30	05/06/1998	NON-POLISHING SACRIFICAL	JANG,
300000				LAYER ETCHBACK	SYUN-MING
				PLANARIZING METHOD FOR	

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Serial#	Patent#	Status	Date Filed	Title	Inventor Name
09086769	Not Issued	30	05/29/1998	CHEMICAL-MECHANICAL POLISH METHOD USING AN UNDOPED SILICON GLASS STOP	JANG , SYUN-MING
09086770	Not Issued	83	05/29/1998	OZONE-TEOS METHOD FOR FORMING WITH ATTENUATED SURFACE SENSITIVITY A	JANG , SYUN-MING
09086772	Not Issued	30	05/29/1998	HARD MASKING METHOD FOR FORMING PATTERNED OXYGEN CONTAINING PLASMA	JANG , SYUN-MING
<u>09086773</u>	Not Issued	30	05/29/1998	HARD MASKING METHOD FOR FORMING OXYGEN CONTAINING PLASMA ETCHABLE	JANG , SYUN-MING
<u>09086775</u>	Not Issued	61	05/29/1998	PREVENTION OF DIE LOSS TO CHEMICAL MECHANICAL POLISHING	JANG , SYUN-MING
09086823	Not Issued	30	05/29/1998	VOID FORMING METHOD FOR FABRICATING LOW DIELECTRIC CONSTANT	JANG , SYUN-MING
<u>09106331</u>	Not Issued	30	06/29/1998	READABLE ALIGNMENT MARK STRUCTURE FORMED USING ENHANCED CHEMICAL	JANG , SYUN-MING
<u>09108866</u>	Not Issued	30	07/01/1998	SHALLOW TRENCH ISOLATION FILLED BY HIGH DENSITY PLASMA CHEMICAL VAPOR	JANG , SYUN-MING
09121708	Not Issued	41	07/24/1998	METHOD OF PHOTO ALIGNMENT FOR SHALLOW TRENCH ISOLATION	JANG , SYUN-MING
09121710	Not	30	07/24/1998	TRENCH FILLING METHOD	JANG,

•	Issued	200		EMPLOYING OXYGEN DENSIFIED GAP FILLING CVD	SYUN-MING
<u>09133972</u>	Not Issued	61	08/14/1998	MULTILAYER INTERLEVEL DIELECTRICS USING PHOSPHORUS-DOPED GLASS	JANG , SYUN-MING
<u>09135045</u>	Not Issued	30	08/17/1998	REGENERATION OF ALIGNMENT MARKS AFTER SHALLOW TRENCH ISOLATION WITH	JANG , SYUN-MING
<u>09149257</u>	Not Issued	30	09/08/1998	VIA FORMATION IN A POLY(ARYLENE ETHER) METAL DIELECTRIC LAYER	JANG , SYUN-MING
<u>09156052</u>	Not Issued	30	09/17/1998	USE OF STOP LAYER FOR CHEMICAL MECHANICAL POLISHING OF CU DAMASCENE	JANG , SYUN-MING
<u>09156058</u>	Not Issued	30	09/17/1998	METHOD OF ENCLOSING COPPER CONDUCTOR IN A DAMASCENE PROCESS	JANG , SYUN-MING
<u>09160965</u>	Not Issued	30	09/25/1998	NOVEL PLANARIZATION METHOD OF COPPER DAMASCENE	JANG , SYUN-MING
<u>09161566</u>	Not Issued	30	09/28/1998	SELECTIVE ELECTROPLATING OF COPPER FOR DAMASCENE PROCESS	JANG , SYUN-MING
<u>09163382</u>	Not Issued	41	09/30/1998	REDUCTION OF VIA OVER ETCHING FOR BORDERLESS CONTACTS	JANG , SYUN-MING
<u>09174660</u>	Not Issued	30	10/19/1998	THERMAL OXIDIZING METHOD FOR FORMING WITH ATTENUATED SURFACE	JANG , SYUN-MING
<u>09177187</u>	Not Issued	30	10/23/1998	DUAL DAMASCENE PATTERNED CONDUCTOR LAYER FORMATION METHOD WITHOUT	JANG , SYUN-MING
<u>09177188</u>	Not Issued	30	10/22/1998	INTEGRATED HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION (HDP-CVD)	JANG , SYUN-MING
<u>09177189</u>	Not Issued	30	10/23/1998	CHEMICAL MECHANICAL POLISH (CMP) PLANARIZING TRENCH FILL METHOD	JANG , SYUN-MING
<u>09182776</u>	Not Issued	30	10/30/1998	SUB-ATMOSPHERIC PRESSURE THERMAL CHEMICAL VAPOR DEPOSITION (SACVD)	JANG , SYUN-MING
09186390	Not Issued	30	11/05/1998	METHOD OF CMP OF POLYSILICON	JANG , SYUN-MING
<u>09192518</u>	Not	30	11/16/1998	METHOD AND APPARATUS FOR	JANG,

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	PLANARIZATION (CMP) OF A	

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Serial#	Patent#	Status	Date Filed	Title	Inventor Name
09192521	Not Issued	30	11/16/1998	SHALLOW TRENCH ISOLATION PROCESS FOR REDUCED JUNCTION LEAKAGE	JANG , SYUN-MING
09196601	Not Issued	41	11/20/1998	MASK PATTERN AND METHOD FOR RECOVERING ALIGNMENT MARKS AFTER CHEMICAL	JANG , SYUN-MING
09216788	Not Issued	30	12/21/1998	CHEMICAL MECHANICAL POLISHING OF POLYSILICON PLUG USING A SILICON	JANG , SYUN-MING
<u>09221965</u>	Not Issued	30	12/28/1998	PASSIVATION METHOD OF POST COPPER DRY ETCHING	JANG , SYUN-MING
09222277	Not Issued	20	12/28/1998	METHOD TO IMPROVE ADHESION BETWEEN LOW DIELECTRIC CONSTANT LAYER AND	JANG , SYUN-MING
09226277	Not Issued	41	01/07/1999	GAP FILLING OF SHALLOW TRENCH ISOLATION BY OZONE-TETRAETHOXYSILANE	JANG , SYUN-MING
09234059	Not Issued	30	01/19/1999	METHOD OF OPTIMIZING DEVICE PERFORMANCE VIA USE OF COPPER DAMASCENE	JANG , SYUN-MING
09234093	Not Issued	30	01/19/1999	METHOD OF REMOVING TUNGSTEN NEAR THE WAFER EDGE AFTER CMP	JANG , SYUN-MING
09236489	Not Issued	30	01/25/1999	SHALLOW TRENCH ISOLATION PLANARIZED BY WET ETCHBACK AND CHEMICAL	JANG , SYUN-MING
09239113	Not Issued	30	01/28/1999	PROTECTION METHOD OF METAL LINES	JANG , SYUN-MING
09244879	Not	30	02/05/1999	NEW SHALLOW TRENCH	JANG,

	Issued			ISOLATION PROCESS	SYUN-MING
09245564	Not Issued	30	02/05/1999	HIGH SELECTIVITY SI-RICH SION ETCH-STOP LAYER	JANG , SYUN-MING
09246295	Not Issued	20	02/08/1999	METAL HILLOCK REDUCTION BY CAPPING WITH A HIGHLY COMPRESSIVE	JANG , SYUN-MING
09248730	Not Issued	41	02/11/1999	METHOD FOR FORMING LOW DIELECTRIC CONSTANT SPIN-ON-POLYMER (SOP)	JANG , SYUN-MING
09252337	Not Issued	30	02/18/1999	WET OXIDATION METHOD FOR FORMING SILICON OXIDE DIELECTRIC LAYER	JANG , SYUN-MING
<u>09252866</u>	Not Issued	30	02/18/1999	METHOD FOR FORMING A STABILIZED FLUOROSILICATE GLASS LAYER	JANG , SYUN-MING
09263563	Not Issued	30	03/08/1999	THE USE OF PE-SION OR PE-OXIDE FOR CONTACT OR VIA PHOTO AND FOR	.1
09266374	Not Issued	30	03/11/1999	REMOVAL OF SION ARC FILM AFTER POLY PHOTO AND ETCH	JANG , SYUN-MING
09268542	Not Issued	30	03/15/1999	VIA PATTERNING FOR POLY(ARYLENE ETHER) USED AS AN INTER-METAL	JANG , SYUN-MING
09270592	Not Issued	41	03/18/1999	LOW DIELECTRIC CONSTANT INTERMETAL DIELECTRIC (IMD) BY FORMATION OF	JANG , SYUN-MING
09282663	Not Issued	30	03/31/1999	METHOD FOR POST PLANARIZATION METAL PHOTOLITHOGRAPHY	JANG , SYUN-MING
09285915	Not Issued	30	04/02/1999	DELAMINATION RESISTANT MULTI-LAYER COMPOSITE DIELECTRIC LAYER	JANG , SYUN-MING
09285916	Not Issued	30	04/02/1999	SHALLOW TRENCH ISOLATION (STI) METHOD WITH REPRODUCIBLE ALIGNMENT	JANG , SYUN-MING
09290924	Not Issued	30	04/12/1999	METHOD FOR MAKING TUNGSTEN METAL PLUGS IN A POLYMER LOW-K INTERMETAL	JANG , SYUN-MING
09292361	Not Issued	30	04/15/1999	REDUCTION OF SURFACE DEFECTS ON AMORPHOUS SILICON GROWN BY A	JANG , SYUN-MING

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Serial#	Patent#	Status	Date Filed	Title	Inventor Name
09298879	Not Issued	20	04/26/1999	FORMATION OF DUAL GATE OXIDE BY TWO-STEP WET OXIDATION	JANG , SYUN-MING
09298930	Not Issued	20		ELIMINATION OF COPPER LINE DAMAGES FOR DAMASCENE PROCESS	JANG , SYUN-MING
09301223	Not Issued	30	}	INTEGRATION OF CMP AND WET OR DRY ETCHING FOR STI	JANG , SYUN-MING
09303836	Not Issued	20	05/03/1999	METHOD TO AVOID METAL SIDE WALL ATTACK FROM F IN HDP-FSG PROCESS	
09304302	Not Issued	20		THE USE OF LOW-HIGH SLURRY FLOW TO ELIMINATE COPPER LINE DAMAGES	JANG , SYUN-MING
<u>08932895</u>	5811345	150		PLANARIZATION OF SHALLOW- TRENCH- ISOLATION	JANG , SYUN-MING JANG

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